

### The reality of Mirrors?

GWADW May 15, 2012

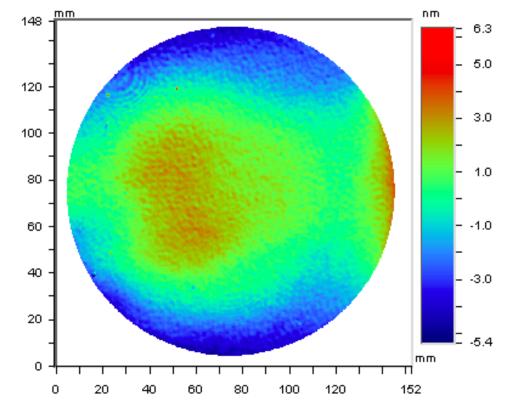
GariLynn Billingsley Liyuan Zhang Zygo... CSIRO...

### Overview

Initial LIGO

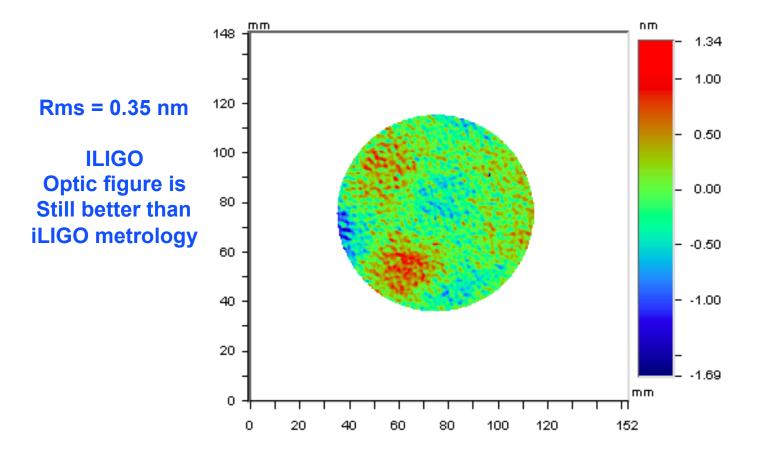
- » Some things we got wrong
- Advanced LIGO
  - » Some things we got right
  - » Some things we're still working on
- Next Generation
  - » Tools we have on hand

## Error in iLIGO calibration file



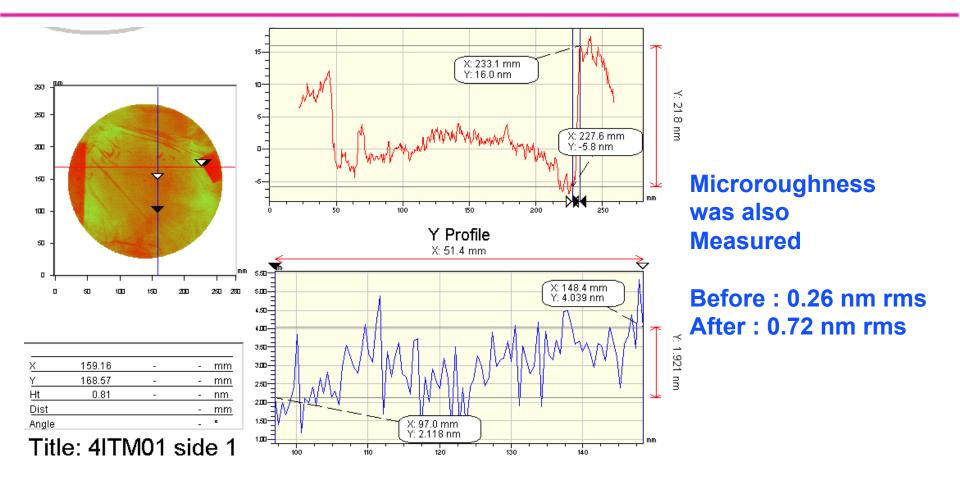
#### 11.7 nm PV over 150mm, Mostly power, The instrument has been realigned, so the original error may be different

# **LIGO** Power subtracted, analyzed over beam size



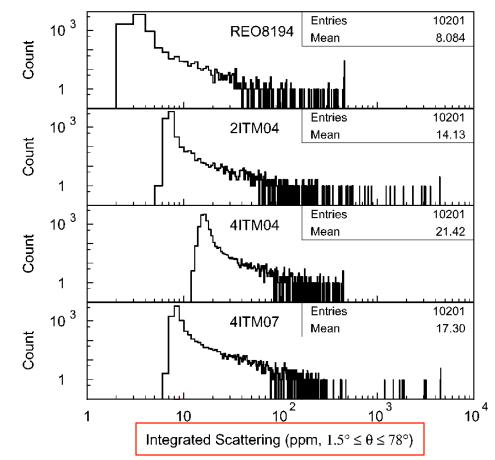


### iLIGO too much cleaning before coating extreme example ~20 nm



## Scatter histograms An indication of etching

- Lower end represents the base microroughness
- High end represents point defects
- See LIGO-G080162 for details





## Advanced LIGO

- Status
- Capability
- Interesting coating behavior
  - » Still in the speculation phase

## LIGO Arm Cavity Loss: Early results are in line with budget

Cavity loss – 2 surfaces (ppm)	Budget 2010 based on specs (ppm)	Actuals 2012 based on (n of 20) (ppm)	
Microroughness scatter	8	2.2 (avg. of 20)	
Defects (Polish, Coating, Contamination)	26	15 (sample of 2) pol, coat	
Coating Absorption*	0.6	0.6 (sample of 2)	
Surface Figure Error & Diffraction	24	3 ppm on coated ITM 21 ppm estimated on coated ETM	
ETM Transmission	5	No data yet	
Total ( required < 75 ppm)	64	42+ ETM trans.	

50ppm budget remaining for contamination and coating induced surface figure error.

\* One TM trial surface had unexplained high absorption – no cause has been identified, no repeat of the problem

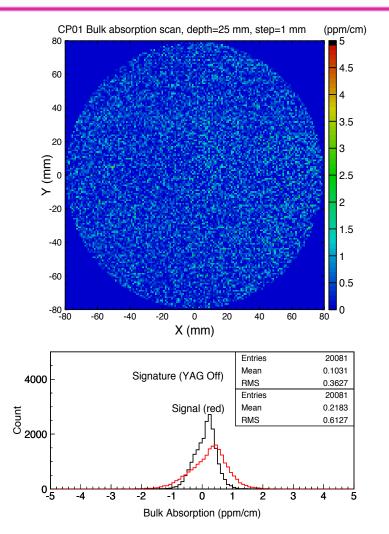
# Quick summary of aLIGO ITM polish

Serial Number	ROC	Figure (-TPA)
ITM01	1939.32	0.10
ITM03	1939.52	0.08
ITM04	1938.61	0.15
ITM05	1939.18	0.10
ITM06	1937.60	0.09
ITM07	1938.53	0.10
ITM08	1938.44	0.16
ITM09	1938.15	0.11
ITM10	1938.15	0.14
ITM11	1939.39	0.18

Follow our progress at https://nebula.ligo.caltech.edu/optics/

### LIGO

# Heraeus 3000 series Suprasil measurable absorption?



OH content for 3000 series is 100 times lower than for the 300 series glass

### Signal (red): 0.21 ppm Background: 0.10 ppm

## Metrology

- Zygo full aperture interferometer is installed and operating at Caltech
- All metrology flats and spheres are complete
- The instrument and environment are quite stable, showing a uniform noise floor of 0.1 to 0.15 nm rms.
  - » Polishing requirement is 0.3 nm rms
  - » Vendor reports some surfaces at 0.08 nm rms
- Good agreement with Polishing vendor measurements

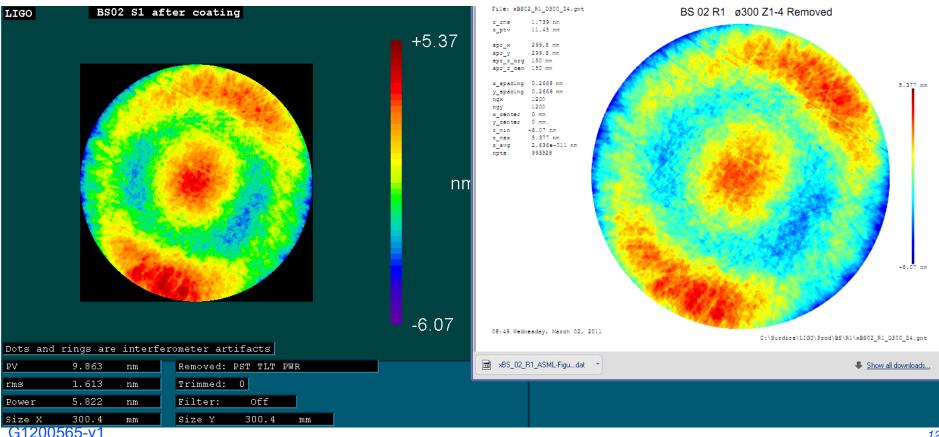


## **LIGO** Figure, before and after coating measured on different instruments

#### Same diameter same color scale

#### LIGO measurement after coating by CSIRO 9.8 nm PV 1.6 nm rms

#### Polisher (Zygo EPO) measurement 11.4 nm PV 1.7 nm rms



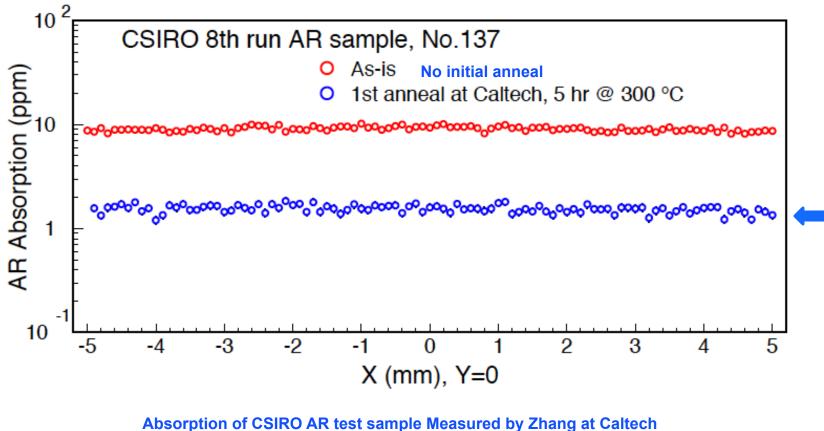
<sup>12</sup> 

# AR coating absorption surprise

- AR coating absorption is not the same as HR
  - » Most IBS HR absorption is now < 1 ppm, AR up to 10 ppm
- Many samples used to explore the parameters
  - » Film thickness thinner is more sensitive to annealing temp
  - » <u>Annealing temperature</u> sensitive to 25 C° variations
- Unintentional experiment:
  - » ~1nm of Silica added to top Silica layer AFTER the initial 400 C anneal (to tune reflectivity)
  - » Second anneal at 300 C° → Absorption of 4 ppm
  - » Third anneal at 400 C  $\rightarrow$  Absorption < 0.5 ppm



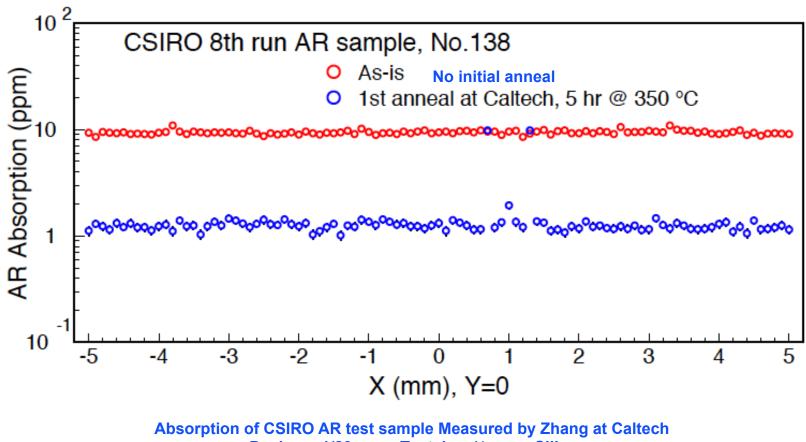
## AR Absorption – 300 C° Too much absorption



Design < 1/20 wave Tantala +  $\frac{1}{4}$  wave Silica

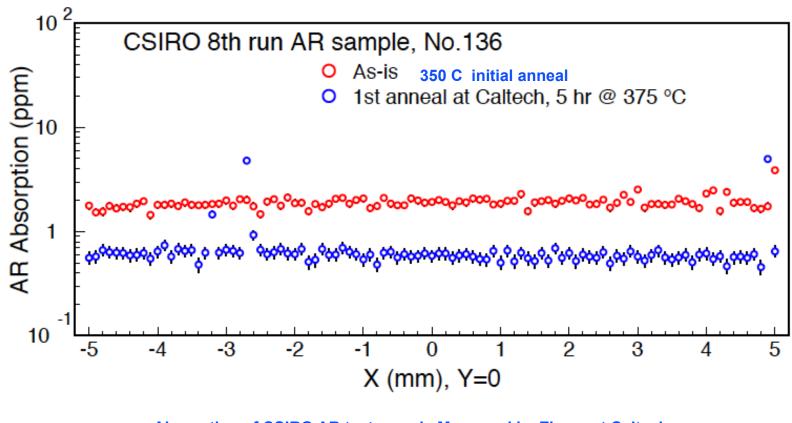


# AR Absorption – 350 C° still too much absorption





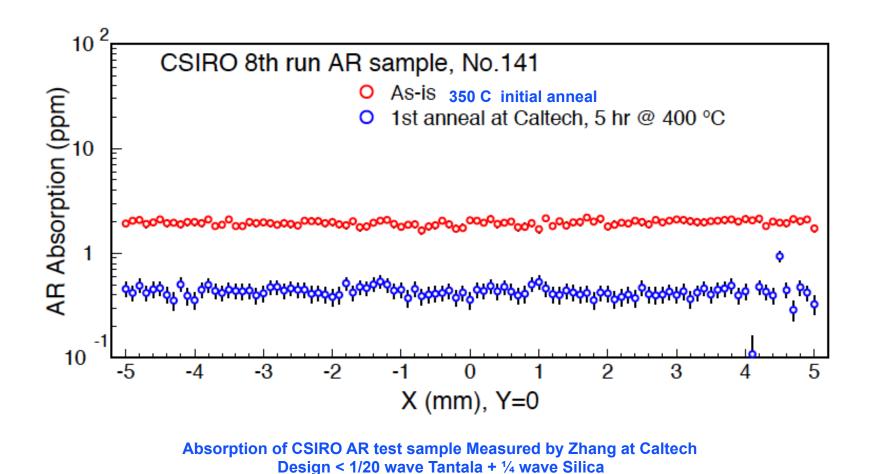
## AR Absorption – 375 C° better



Absorption of CSIRO AR test sample Measured by Zhang at Caltech Design < 1/20 wave Tantala + 1/4 wave Silica

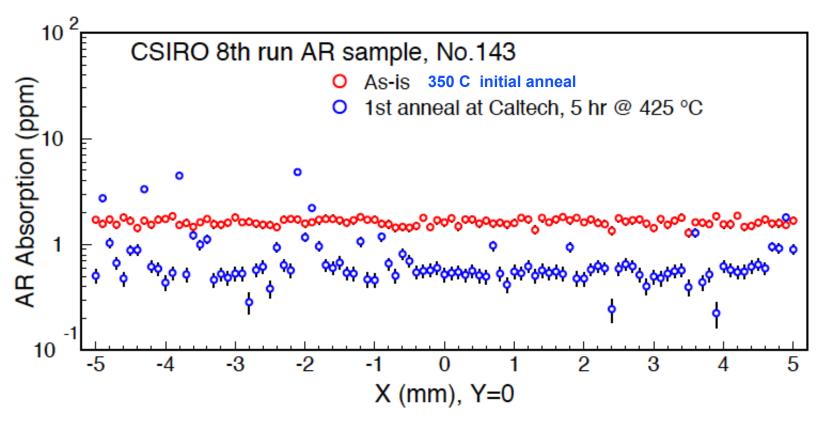


## AR Absorption – 400 C° even better





## AR Absorption – 425 C° too far!



Absorption of CSIRO AR test sample Measured by Zhang at Caltech Design < 1/20 wave Tantala + 1/4 wave Silica



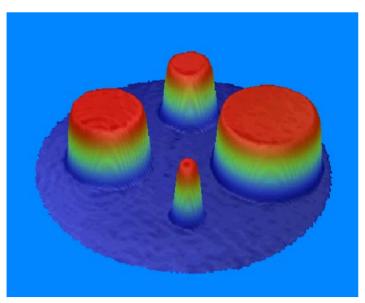
### Next generation

• Thinking about non-spherical surfaces ....

## LIGO

### Future – sculpt your own surface

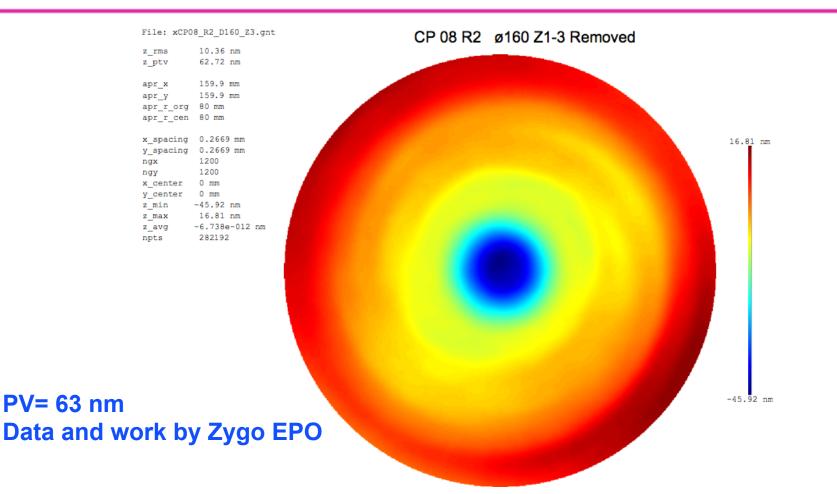
- Difference from a sphere
  - » < 100 nm in any area where scatter loss is important
  - » Surface slope up to ~ 20nm/mm
  - » Current vendors can't handle much larger optics
- Ion beam figuring can sculpt silicon as well as silica... others.



This data is inverted for display, ion beams removed material

Data and demonstration by CSIRO

## **LIGO** Correcting inhomogeneity of Heraeus 3001 by Ion beam figuring of side 2



## **LIGO** Resulting Transmitted wavefront Corrected s2 plus bulk

File: xCP08_S	Single_Pass_TWE_D160_Z6.gnt	CP 08 Single Pass TWE	ø160 Z1-6 Removed	
	.2415 nm	3		
z_ptv 2.	.023 nm			
	59.9 mm			
	59.9 mm			
apr_r_org 80				
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	.105 nm			
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	82192	1 I I I I I I I I I I I I I I I I I I I		
n 24 nm 1 work I O	oy			-0.918 nm

**PV= 2 nm** rms = 0.24 iData and w Zygo EPO



## Summary

• Part per million losses matter!!!

• We know a lot more about cleaning and metrology

• We are well positioned to handle an optical upgrade as long as the test mass size does not increase dramatically